

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Original) A carrier constructed to carry a lithographic substrate or a lithographic patterning device, said carrier comprising:
a first member provided with an open hollow structure that is open to at least one side of said first member, said first member constructed to support a lithographic substrate or a lithographic patterning device; and
a second member connected to said first member, such that a closed hollow internal structure is formed between said first and second members.
2. (Original) A carrier according to claim 1, wherein said second member has an open, hollow structure which together with said open hollow structure of said first member forms said closed internal structure of said carrier.
3. (Original) A carrier according to claim 2, wherein said open, hollow structure of said first and second members includes a plurality of spaced apart ribs.
4. (Currently Amended) A carrier according to claim 1, further comprising:
a third member positioned between said first and second ~~member~~ members, said third member having an open, hollow structure, that is open to two opposite sides thereof.
5. (Previously Presented) A carrier according to claim 4, wherein said third member includes a plurality of spaced apart interior walls in said open, hollow structure.
6. (Original) A carrier according to claim 3, wherein said open, hollow structure of said first and second members includes an additional plate positioned against said ribs.

7. (Original) A carrier according to claim 1, wherein said first and second members of said carrier are made of different materials, of which at least one is chosen from a group consisting of glass, carbon and ceramics.

8. (Original) A lithographic apparatus comprising:
a radiation system constructed to provide a beam of radiation;
a support structure constructed to support a patterning device, said patterning device serving to impart a cross-section of said beam with a pattern to form a patterned beam; and
a projection system that projects said patterned beam onto a target portion of a substrate, wherein said apparatus further includes a table constructed to hold said substrate or said patterning device, said table including a carrier constructed to carry a lithographic substrate or a lithographic patterning device, said carrier including
a first member provided with an open hollow structure that is open to at least one side of said first member, said first member constructed to support a lithographic substrate or a lithographic patterning device; and
a second member connected to said first member, such that a closed hollow internal structure is formed between said first and second members.

Claims 9 – 18 (Cancelled).

19. (New) A lithographic apparatus according to claim 8, wherein said second member has an open, hollow structure which together with said open hollow structure of said first member forms said closed internal structure of said carrier.

20. (New) A lithographic apparatus according to claim 19, wherein said open, hollow structure of said first and second members includes a plurality of spaced apart ribs.

21. (New) A lithographic apparatus according to claim 20, wherein said open, hollow structure of said first and second members includes an additional plate positioned against said ribs.

22. (New) A lithographic apparatus according to claim 8, wherein said carrier further includes a third member positioned between said first and second members, said third member having an open, hollow structure, that is open to two opposite sides thereof.

23. (New) A lithographic apparatus according to claim 22, wherein said third member includes a plurality of spaced apart interior walls in said open, hollow structure.

24. (New) A lithographic apparatus according to claim 8, wherein said first and second members of said carrier are made of different materials, of which at least one is chosen from a group consisting of glass, carbon and ceramics.